



PATENT

Atty. Docket No. 007996 USA CO1/IMPLANT/CONDUCTIVE/JB1
Express Mail Label No. EV 386865035 US

IN THE UNITED STATES PATENT AND TRADEMARK OFFICE

Appl. No. : 10/694,162
Applicant : Donald W. Berrian
Filed : 27 October 2003
Title : SYSTEM AND METHOD FOR IMPLANTING A WAFER
WITH AN ION BEAM
TC/A.U. : 2881
Examiner : David A. Vanore
Confirmation No. : 3050

Mail Stop Amendment
Commissioner for Patents
P.O. Box 1450
Alexandria, VA 22313-1450

RESPONSE TO OFFICE ACTION

Sir:

The Examiner's comments presented in the Office Action mailed 29 March 2004 have been carefully considered and are addressed in the remarks provided herein as follows:

Remarks/Arguments begin on page 2 of this paper.

06/25/2004 JBALINAN 00000016 10694162

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